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				Application Number	
				Filing Date	
				First Named Inventor	Peng Zhang, et al.
				Art Unit	
				Examiner Name	
Sheet	1	of	2	Attorney Docket Number	06491 USA

U. S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US- 2002/163629 A1	11/7/2002	M. Switkes, et al.	
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FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				
		WO 03/077034 A2	9/18/2003	World		✓

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NON PATENT LITERATURE DOCUMENTS			
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		A.K. RAUB, et al., "Deep UV Immersion Interferometric Lithography," <i>Proceedings of SPIE</i> , Vol. 5040, pp. 667-678 (2003).	
		M. SWITKES, et al., "Immersion Lithography: Beyond the 65nm Node With Optics," <i>Microlithography World</i> , 12(2), 4-6, 18, 20 (2003).	
		M. SWITKES, et al., "Immersion Liquids for Lithography in the Deep Ultraviolet," <i>Proceedings of SPIE</i> , Vol. 5040, pp. 690-699 (2003).	
		S. OWA, et al., "Immersion Lithography: Its Potential Performance and Issues," <i>Proceedings of SPIE</i> , Vol. 5040, pp. 724-730 (2003).	

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